

Special Issue

Photonic Technology for Precision Metrology

Message from the Guest Editor

This issue focuses on metrology principles and measurement instrumentation in optical technology to solve challenging engineering problems.

Technical topics include (but are not limited):

- optical imaging and reflectometry;
- interferometry and spectroscopy;
- radiometry and photometry;
- remote and in-situ sensing;
- optoelectronic sensors and smart-sensors;
- optical sensors for robots and unmanned systems;
- industrial optical measurements;
- high resolution optical metrology;
- fiber-optic measurements;
- optical frequency metrology and optical clocks;
- optical sources and detectors;
- photonic metrological technology for science, environment, medicine, security, telecommunication, and space.

Guest Editor

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Deadline for manuscript submissions

closed (20 January 2022)



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About the Journal

Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

Editor-in-Chief

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